



AUG 13 2004

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Attorney Docket No.: 60919 (70551)

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re application of: Tetsuya INUI, et al.

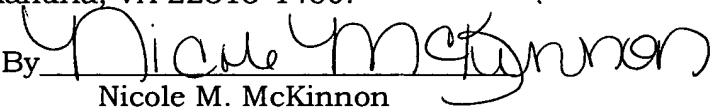
U.S.S.N.: 10/789,085 Group No.: 2872

Filed: February 27, 2004 Examiner: Not Yet Assigned

For: CRYSTAL GROWTH APPARATUS AND CRYSTAL GROWTH
METHOD FOR SEMICONDUCTOR THIN FILM

CERTIFICATE OF EXPRESS MAILING (Label No.: EV 438977383 US)

I hereby certify that this correspondence is being deposited with the United States Postal Service "Express Mail Post Office to Addressee" service under 37 C.F.R. section 1.10, on August 11, 2004 and is addressed to Mail Stop AMENDMENT, Commissioner for Patents, P.O. Box 1450, Alexandria, VA 22313-1450.

By 
Nicole M. McKinnon

Mail Stop AMENDMENT
Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

Sir:

INFORMATION DISCLOSURE STATEMENT/REPLACEMENT 1449

An Information Disclosure Statement was filed on February 24, 2004 in the above-referenced U.S. patent application. Applicants subsequently noticed that one of the patents listed on the PTO-1449 was misidentified. As such, submitted herewith is a replacement 1449 in which all of the submitted references are correctly identified.

Please note the correct references were previously submitted with the Information Disclosure Statement filed on February 24, 2004, and are not being re-submitted.

Applicant believes that no fees are due in this matter. However, if for any reason a fee is required, a fee paid is inadequate or credit is owed for any excess fee paid, the Commissioner is hereby authorized and requested to charge Deposit Account No. **04-1105**.

Date: August 11, 2004
Customer No.: 21874

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REPLACEMENT 1449 FORM

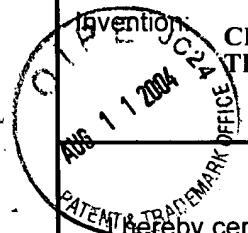
FORM PTO-1449 INFORMATION DISCLOSURE STATEMENT			DOCKET NO.:		SERIAL NO.:		
			60919 (70551)		10/789,085		
			APPLICANT(S): Tetsuya INUI, et al.				
			FILING DATE: February 27, 2004		GROUP NO.: Not Yet Assigned		
UNITED STATES PATENT DOCUMENTS							
EXAM. INITIALS		DOCUMENT NUMBER	DATE	NAME	CLASS	SUBCLASS	FILING DATE IF APPROPRIATE
FOREIGN PATENT DOCUMENTS							
		DOCUMENT NUMBER	DATE	COUNTRY	CLASS	SUBCLASS	TRANSLATION YES/NO
	BA	11-307450	11/05/99	JAPAN	H01L	21/20	ABSTRACT
	BB	58-201326	11/24/83	JAPAN	H01L	21/26	ABSTRACT
	BC	2000-505241	04/25/00	JAPAN	H01L	21/20	NO
OTHER DOCUMENTS (INCLUDING AUTHOR, TITLE, DATE, PERTINENT PAGES, ETC.)							
	CA	Akito Hara, et al., "Nucleus Formation Site of Silicon on Glass and Solidification Direction Control – Aiming to Form Monocrystalline Silicon Si-TFT" Textbook of the 112 th workshop of Division of Materials Science and Crystal Technology of the Japan Society of Applied Physics, Division of Materials Science and Crystal Technology of the Japan Society of Applied Physics, pp. 19-25 (2000).					
EXAMINER:					DATE:		

CERTIFICATE OF MAILING BY "EXPRESS MAIL" (37 CFR 1.10)

Applicant(s): Tetsuya INUI, et al.

Docket No.

60919 (70551)

Serial No.
10/789,085Filing Date
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Not Yet AssignedGroup Art Unit
2872

CRYSTAL GROWTH APPARATUS AND CRYSTAL GROWTH METHOD FOR SEMICONDUCTOR THIN FILM

I hereby certify that the following correspondence:

Information Disclosure Statement/Replacement 1449 (along with related documents)*(Identify type of correspondence)*

is being deposited with the United States Postal Service "Express Mail Post Office to Addressee" service under 37 CFR 1.10 in an envelope addressed to: Commissioner for Patents, P.O. Box 1450, Alexandria, VA 22313-1450 on **Mail Stop AMENDMENT**

August 11, 2004*(Date)***Nicole M. McKinnon***(Typed or Printed Name of Person Mailing Correspondence)**(Signature of Person Mailing Correspondence)***EV 438977383 US***("Express Mail" Mailing Label Number)*

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